

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Thomas A. Figura, Kevin Donohoe, & Thomas Dunbar

Group Art Unit:

Serial No.:

09/471,460

Application Examiner:

Calvin Lee

Filed:

December 22, 1999

Atty. Docket:

94-0280.03

Title: USE OF A PLASMA SOURCE TO FORM A LAYER

DURING THE FORMATION OF A SEMICONDUCTOR DEVICE

RECEIVED TECHNOLOGY CENTER 2800

AMENDMENT AFTER THE CONTINUED PROSECUTION APPLICATION

AND RESPONSE TO THE OFFICE ACTION DATED JUNE 6, 2000

Assistant Commissioner for Patents Washington, D.C. 20231

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I HEREBY CERTIFY THAT THIS PAPER IS BEING DEPOSITED WITH THE UNITED STATES POSTAL SERVICE "EXPRESS MAIL POST OFFICE TO ADDRESSEE" SERVICE UNDER 37 C.F.R § 1.10 ON THE DATE INDICATED ABOVE AND IS ADDRESSED TO THE ASSISTANT COMMISSIONER

PATENTS, WASHINGTO

Signature

Dear Sir:

Applicants submit this Amendment and Response to the Office Action dated June 6, 2000. Please amend the accompanying continued prosecution application as follows.

IN THE SPECIFICATION

In the section labeled "RELATED APPLICATIONS" added in the Preliminary Amendment, please add at the end of that section the following:

This application contains subject matter related to U.S. application Ser. No. 09/470, 650, which is also a divisional of pending U.S. application Ser. No. 09/046,835 mentioned above.